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INSPECTING DEVICE

Patent Number: JP61169750
Publication date: 1986-07-31
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Requested Patent: ☐ JP61169750
Application Number: JP19850009027 19850123
Priority Number(s):
IPC Classification: G01N21/88; G01B11/30; H01L21/66
EC Classification:
Equivalents:

Abstract

PURPOSE: To prevent possible erroneous decision, by irradiating an object to be inspected with an S polarized light and P polarized light while the P polarized light component alone is detected among the lights reflected on the object being inspected.
CONSTITUTION: When a P polarized light and an S polarized light is made to irradiate a defect on a wafer 1 from laser light sources 4 and 5 of an illuminator 3, the P polarized light component is contained in the reflected light thereof. The P polarized light component is detected intensely with a photo detector 8 as transmitted through a polarization plate 7. This causes a very large difference in the level between the signal involved in the detection of the defect and the signal done in the detection of a pattern and thus, almost eliminate the possibility of erroneous decision overlooking the defect regardless of relax of the threshold in the detection of a defect by comparing two pellets.

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